

U.S. Department of Commerce, Patent and Trademark Office	Serial No.:
	Filing Date: 09/16/2003
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventors: David S. Zuck and Kurtis R. Macura
(Use several sheets if necessary)	Group Art Unit: Unknown 1746
"Steam Cleaning System and Method for Semiconductor Process Equipment"	Examiner Name: Unknown Carrell
	Attorney Docket No. QC-001-1C

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
BSC	AA	4,083,946	04/1978	Schurr et al.	423	613	
	AB	5,172,728	12/1992	Tsukazaki, Hideo	137	637.2	
	AC	5,545,289	06/1996	Chen et al.	438	694	
	AD	6,146,469	11/2000	Toshima, Masato	134	37	
BSC	AE	6,460,552	10/2002	Lorimer, D'Arcy H.	134	148	

Foreign Patent Documents

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
BSC	AF	JP 407273078A	10/1995	Japan	—	—		
BSC	AG	EP0489179A1	06/1992	Europe	—	—		

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BSC	AH	CRC Handbook of Chemistry and Physics, A Ready-Reference Book of Chemical and Physical Data, cover sheet, 8-102 and 8-103. 1999-2000, 80 th edition. CRC Press (Boca Raton, London, New York, and Washington D.C.)						
	AI							
	AJ							
	AK							

Examiner *SCell*Date Considered *6/3/04*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.